

SEM 2015

October 20-22, 2015, Göteborg, SWEDEN

SEM 2015 -- Lab stations

Lab station 1:

TESCAN FERA 3, plasma source FIB with SEM

- electron source: Schottky FEG

Lab station 2:

Fei Versa 3D DualBeam

- electron source: Schottky FEG

Lab station 3:

Zeiss Sigma HD VP FEG-SEM

- electron source: Schottky FEG
- Bruker XEDS system, 100 (mm)² X-ray detector

Light optical microscope AXIO-imager with correlative microscopy

Lab station 4:

Hitachi SU3500 VP-SEM

- electron source: W filament
- Bruker XEDS system

Hitachi TM3000plus table top SEM

Hitachi IM4000 Ion Milling System

Lab station 5:

JEOL JCM-NeoScope, table top SEM with W-emitter

Lab station 6:

Phenom XL, table top SEM

- electron source: thermoionic, CeB₆
- integrated XEDS system

Lab station 7:

Fei ESEM Quanta 200 FEG

- Oxford X-Max^N 80 silicon drift detector
- Oxford AZtec Automated EDS system

Lab station 8:

Zeiss / Leo Ultra 55 FEG-SEM

- Bruker Quantax EDS system
- Bruker Quantax EBSD with OPTIMUS

Lab station 9:

Leica TIC 3X, specimen preparation - milling

Leica TXP, specimen preparation - sawing, grinding, polishing

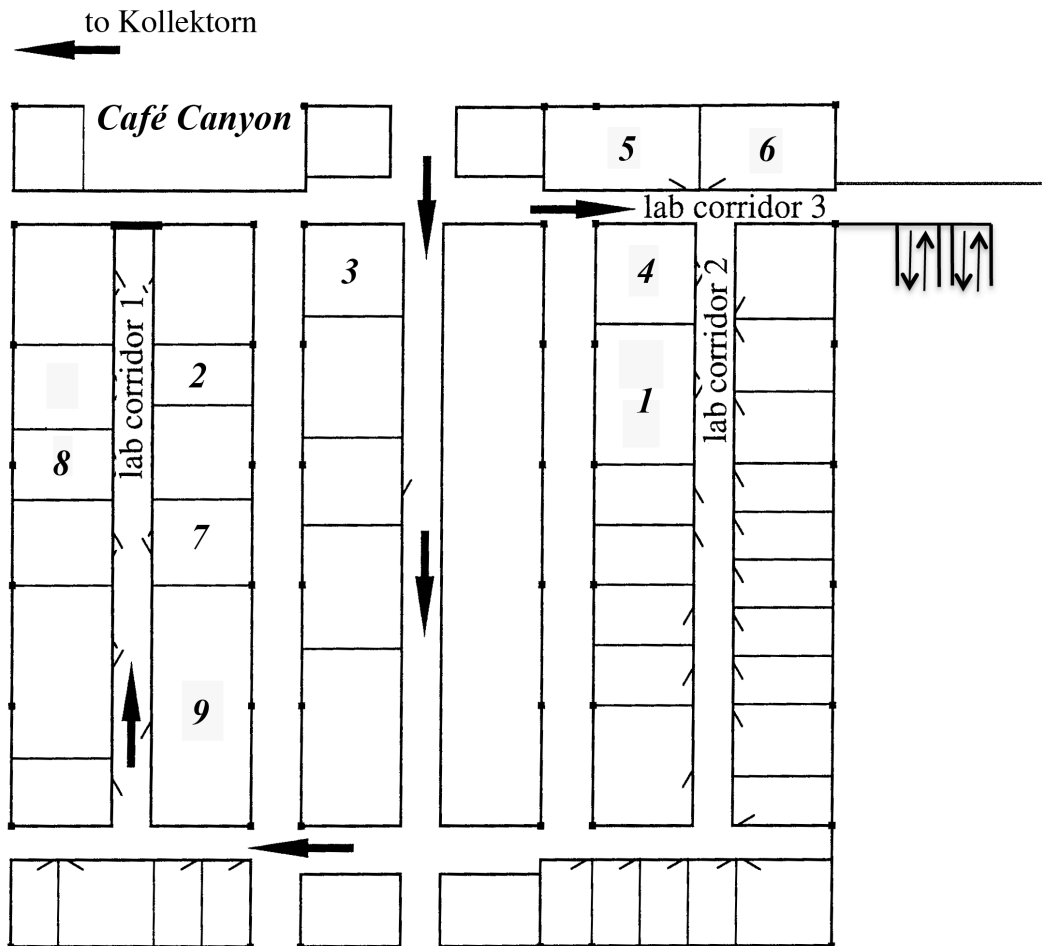
Leica ACE600, specimen preparation - coating

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SEM 2015 - lab floor plan

CANYON



1. TESCAN
2. FEI
3. ZEISS
4. HITACHI
5. JEOL
6. PHENOM
7. OXFORD
8. BRUKER
9. LEICA